

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: **Hiroyuki HYODO et al.**

Serial Number: **Not Yet Assigned**

Filed: **September 16, 2003**

**Customer No.: 23850**

For: **SOLID MATERIAL GASIFICATION METHOD, THIN FILM FORMATION  
PROCESS AND APPARATUSES**

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

September 16, 2003

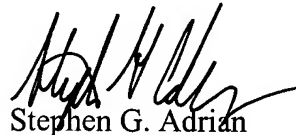
Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 01-2340.

Respectfully submitted,  
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Enclosures: PTO-1449; References (3)

<b>INFORMATION DISCLOSURE STATEMENT PTO-1449</b>	Atty. Docket No. 031161	Serial No. New Appln.
	Applicant(s): Hiroyuki HYODO et al.	
	Filing Date: September 16, 2003	Group Art Unit:

### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

### FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)
_____ AE 5-311446	11/22/93	Japan	Abstract. Cited in the specification.
_____ AF 7-76778	03/20/95	Japan	Abstract. Cited in the specification.
_____ AG 10-298762	11/10/98	Japan	Abstract. Cited in the specification.
_____ AH			
_____ AI			

### OTHER DOCUMENTS

_____ AJ	
_____ AK	
Examiner.	Date Considered